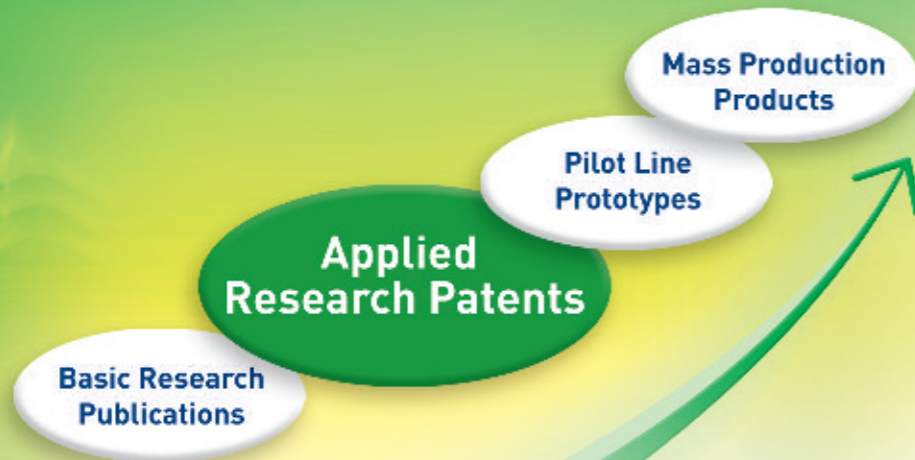


LETI's positioning



FROM RESEARCH TO INDUSTRY

Research programs at a glance



More than 40 years of history

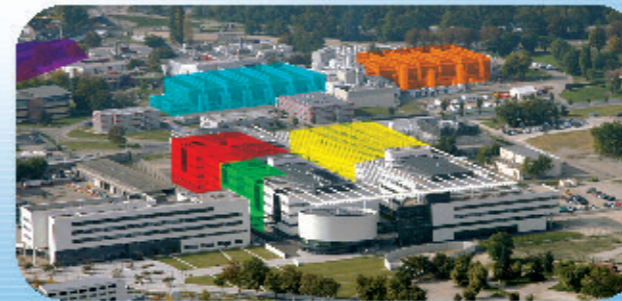
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|--|------|
| opening of a complete 300 mm fab dedicated to 3D integration | 2010 |
| launch of Clineat | 2009 |
| IBM CMOS Alliance | 2009 |
| Caltech Alliance | 2008 |
| opening of a new 200 mm line dedicated to MEMS | 2006 |
| Inauguration of Minatoc Campus | 2006 |
| first silicon gyrometer MEMS developed and transferred on 200 mm wafers | 2002 |
| 1 st 20 nm transistor produced by Leti | 1999 |
| Soitec created, start-up of Leti | 1992 |
| sensor technology transferred to Terralton | 1987 |
| Sofradir created, a spin-off of Leti | 1986 |
| silicon accelerometer patented | 1983 |
| first French X scanner designed and built at Leti | 1976 |
| Efcis spun off specialist for on-demand production of MOS circuits, (to become ST in 1992) | 1972 |
| creation of Leti | 1967 |
| first French integrated circuit produced by the CENG "electronics section" | 1963 |



Facts and figures

- ➔ **1,600 researchers**
- ➔ 50 post-docs
- ➔ 200 thesis
- ➔ 200 internships
- ➔ 230 M€ budget
- ➔ 35 M€ CapEx
- ➔ Portfolio 1,700 patents
- ➔ 37 start-ups created
- ➔ 23 common laboratories with industrial partners

A complete set of research platforms



| | | | | | |
|--------------------------|----------------------------|-------------------------|------------------------------|----------|---------------------------------|
| | | | | | |
| ➔ 300 mm nanoelectronics | ➔ 200 mm advanced « CMOS » | ➔ More Than Moore 200mm | ➔ Nanoscale Characterization | ➔ Design | ➔ Microtechnologies for biology |